

New Release

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ANALYSIS REPORT OF TRANSFORM 'TPH3207WS' 650V POWER GaN FET

April 2018. LTEC Corporation released a detailed structure analysis report of this 650V GaN FET. This product has 50A output current capability, which is the almost double comparing with other GaN devices. This FET is a cascode arrangement using a low-voltage Si-FET device in order to realize a normally OFF configuration.



Package top view

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Die top view

Device features

- Max. operating voltage: 650V, rated DC Drain current ID=50A at Tj=25°C
- ON-resistance, RON = $41m\Omega$

Key analysis results

- Actual break-down voltage BVdss=1700V. It has wide margin compared with operating voltage specification (Vdss=650)→Twice lager than other GaN's.
- Countermeasures of device structure and layout for JEDEC compliant
- Stacked structure (GaN device and low voltage Si-FET) to fit in TO-247
- The countermeasure for Gate abnormal oscillation and ringing

The 155 pages report includes

- 1. The comparison with other GaN power devices,
- 2. Package cross section and EDX analysis
- 3. Die plan analysis
- 4. Die cross section (SEM, TEM), epi layer TEM-EDX material analysis
- 5. Electrical characteristic measurement (Ron, leakage current-vs-temperature, break down voltage and Drain capacitance(Coss vs Vds)

Price for sales: \$7,200.00

Note: The listed report price may not be accurate as it decreases over time.

Please contact us for current report pricing: info@ltecusa.com

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Note1: Device temperature is as the parameter.



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